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U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

APPL NUM 10004489	FILING DATE 10/23/2001	CLASS 438	SUBCLASS 2812	GAU 2812	EXAMINER P.
**APPLICANTS: Suzuki Yoichi; Shimayama Tsutomu;					
**CONTINUING DATA VERIFIED:					
**FOREIGN APPLICATIONS VERIFIED: JAPAN P2000-322849 10/23/2000					
PG-PUB DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>			
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no		35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no		ATTORNEY DOCKET NO SOEI/0011	
Verified and Acknowledged Examiner's Initials					
TITLE : Method of forming film, method of manufacturing semiconductor device, and film forming apparatus					
U.S. DEPT. OF COMMERCE PAT & TM-PTO-435L (Rev. 12-94)					

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		Primary Examiner	DRAWING	
Amount Due	Date Paid		Sheets Drwg.	Figs. Drwg.
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	Application Examiner	
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